

L Numb r	Hits	Search T xt	DB	Time stamp
84	7562	(tft r (thin near film n ar transist r)).clm.	USPAT; US-P PUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:59
85	1159	(tft or (thin near film near transistor)).clm. and sensor	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:59
86	278	(tft or (thin near film near transistor)).clm. and sensor.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:59
87	9	(tft or (thin near film near transistor)).clm. and sensor.clm. and (resistor or piezoresistor or piezo-resistor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:01
88	739	(tft or (thin near film near transistor)) and sensor and (resistor or piezoresistor or piezo-resistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:01
89	363	(tft or (thin near film near transistor)) and sensor and (resistor or piezoresistor or piezo-resistor) and (beam or cantilever or diaphragm or membrane)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:01
90	343	(tft or (thin near film near transistor)) and sensor and (resistor or piezoresistor or piezo-resistor) and (beam or cantilever or diaphragm or membrane) and (substrate or glass)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:01
91	92	(tft or (thin near film near transistor)) and sensor.ti,ab,clm. and (resistor or piezoresistor or piezo-resistor) and (beam or cantilever or diaphragm or membrane) and (substrate or glass)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:02
92	28	(tft or (thin near film near transistor)) and sensor.ti,ab,clm. and (resistor or piezoresistor or piezo-resistor) and (beam or cantilever or diaphragm or membrane).ti,ab,clm. and (substrate or glass)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:02

93	5	(tft or (thin near film near transistor)) and sensor.ti,ab,clm. and (resistor or piezoresistor or piezo-resistor).ti,ab,clm. and (beam or cantilever or diaphragm or membrane).ti,ab,clm. and (substrate or glass)	USPAT; US-P PUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:10
94	0	(tft or (thin near film near transistor)).ti,ab,clm. and sensor.ti,ab,clm. and (resistor or piezoresistor or piezo-resistor).ti,ab,clm. and (beam or cantilever or diaphragm or membrane).ti,ab,clm. and (substrate or glass)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:05
95	1813	(tft or (thin near film near transistor)).ti,ab,clm. and sensor.ti,ab,clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:05
96	0	(tft or (thin near film near transistor)).ti,ab,clm. and (acceleration near sensor).ti,ab,clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:05
97	2881	(tft or (thin near film near transistor)) same sensor	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:05
98	76	(tft or (thin near film near transistor)) same sensor same (membrane or cantilever or diaphragm or beam)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:06
99	0	(tft or (thin near film near transistor)) same sensor same (membrane or cantilever or diaphragm or beam) same (resistor or piezoresistor or piezo-resistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:06
100	6020	sensor and (tft or (thin near film near transistor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:11
101	2385	sensor and (tft or (thin near film near transistor)) and (beam or cantilever or diaphragm or membrane)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:11
102	363	sensor and (tft or (thin near film near transistor)) and (beam or cantilever or diaphragm or membrane) and (resistor or piezoresistor or piezo-resistor)	USPAT; US-P PUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:11

103	103	sensor and (tft or (thin near film near transistor)) and (beam or cantilever or diaphragm or membrane) and (resistor or piezoresistor or piezo-resistor) and sensor.ti,ab,clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:12
104	31	sensor.ti,ab,clm. and (tft or (thin near film near transistor)) and (beam or cantilever or diaphragm or membrane).ti,ab,clm. and (resistor or piezoresistor or piezo-resistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:12
105	7	sensor.ti,ab,clm. and (tft or (thin near film near transistor)) and (beam or cantilever or diaphragm or membrane).ti,ab,clm. and (resistor or piezoresistor or piezo-resistor).ti,ab,clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 21:12

L Numb r	Hits	Search T xt	DB	Time stamp
54	7	(a c l rati n n ar sensor).clm. and (piez resist r or (pi zo-r sist r)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:30
55	6	(acceleration near sensor).clm. and (piezoresistor or (piezo-resistor)).clm. and beam.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:30
56	0	(acceleration near sensor).clm. and (piezoresistor or (piezo-resistor)).clm. and beam.clm. and glass.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:30
57	4	(acceleration near sensor).clm. and (piezoresistor or (piezo-resistor)).clm. and beam.clm. and substrate.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:32
58	4	(acceleration near sensor).clm. and (piezoresistor or (piezo-resistor)).clm. and (membrane or cantilever or beam).clm. and substrate.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:34
59	6	(tft or (thin near film near transistor)) and (beam or cantilever or membrane) and (piezoresistor or piezo-resistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:35
60	6	(tft or (thin near film near transistor)) and (diaphragm or beam or cantilever or membrane) and (piezoresistor or piezo-resistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:38
61	8222	(tft or (thin near film near transistor)) and (diaphragm or beam or cantilever or membrane) and (piezoresistor or piezo-resistor or resistor or (thin near film near transistor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:39
62	19	(tft or (thin near film near transistor)) and (diaphragm or beam or cantilever or membrane) and (piezoresistor or piezo-resistor or resistor or (thin near film near transistor)) and (acceleration near sensor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:40

63	3	(tft or (thin n ar film near transist r)).ti,ab,clm. and (diaphragm r beam r cantil ver r membrane) and (piez r sistor r pi zo-resist r or resistor r (thin n ar film near transist r)) and (accelerati n near sens r)	USPAT; US-P PUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:42
64	215	(piezoresistor or piezo-resistor or (thin near film near resistor)) same (control or controller or controlling or controlled or circuit or circuitry or tft or (thin near film near transistor)) same beam	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:43
65	56	(piezoresistor or piezo-resistor or (thin near film near resistor)) same (control or controller or controlling or controlled or circuit or circuitry or tft or (thin near film near transistor)) same beam same sensor	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:43
66	22	(piezoresistor or piezo-resistor or (thin near film near resistor)) same (control or controller or controlling or controlled or circuit or circuitry or tft or (thin near film near transistor)) same beam same sensor same (substrate or glass)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:45
67	0	(piezoresistor or piezo-resistor or (thin near film near resistor)) same (control or controller or controlling or controlled or circuit or circuitry or tft or (thin near film near transistor)) same beam same sensor same (substrate or glass) and (tft or (thin near film near transistor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:45
68	6	(piezoresistor or piezo-resistor or (thin near film near resistor)) same (control or controller or controlling or controlled or circuit or circuitry or tft or (thin near film near transistor)) same beam same sensor same (substrate or glass) and (tft or transistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:46
69	2	(piezoresistor or piezo-resistor or (thin near film near resistor)) same (control or controller or controlling or controlled or circuit or circuitry or tft or (thin near film near transistor)) same beam same sensor same (substrate or glass) and (tft or transistor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:47
70	751	(piezoresistor or piezo-resistor or (thin near film near resistor)) near10 (beam or cantilever or diaphragm or membrane)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:47
71	354	((pi zoresistor r piez -resist r or (thin n ar film n ar resistor)) near10 (beam or cantilever r diaphragm or membrane)).ti,ab, lm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:48

72	111	((piezor sisto r pi z -resist r or (thin near film near resistor)) n ar10 (b am or cantil v r or diaphragm or m mbrane)).clm.	USPAT; US-P PUB; EP ; JPO; DERWENT; IBM_TDB	2004/05/16 20:48
73	3	((piez r sist r or piezo-resistor or (thin near film near resistor)) near10 (beam or cantilever or diaphragm or membrane)).clm. and (acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:50
74	0	((piezoresistor or piezo-resistor or (thin near film near resistor)) same (beam or cantilever or diaphragm or membrane) same (glass or substrate)).clm. and (acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:50
75	420	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:52
76	358	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near transistor)).clm. and (transistor or circuit or circuitry or tft).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:52
77	55	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:52
78	24	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm. and sensor.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:54
79	0	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm. and sensor.clm. and "349"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:54
80	9	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm. and sensor.clm. and "257"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:55

81	6	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm. and sensor.clm. and "257" and ((piezoresistor or piezo-resistor or (thin near film near resistor)) near10 (beam or cantilever or membrane or diaphragm)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:56
82	2	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm. and sensor.clm. and "257" and ((piezoresistor or piezo-resistor or (thin near film near resistor)) near10 (beam or cantilever or membrane or diaphragm)).clm. and ((circuit or circuitry or control or controller or controlling or controlled or tft or transistor) same (piezoresistor or piezoresistor or resistor or (thin near film near resistor)) same (beam or cantilever or diaphragm or membrane)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:58
83	3	(glass or substrate).clm. and (beam or cantilever or diaphragm or membrane).clm. and (piezoresistor or piezo-resistor or (thin near film near resistor)).clm. and (transistor or circuit or circuitry or tft).clm. and sensor.clm. and "257" and ((piezoresistor or piezo-resistor or (thin near film near resistor) or resistor) near10 (beam or cantilever or membrane or diaphragm)).clm. and ((circuit or circuitry or control or controller or controlling or controlled or tft or transistor) same (piezoresistor or piezoresistor or resistor or (thin near film near resistor)) same (beam or cantilever or diaphragm or membrane)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/16 20:59